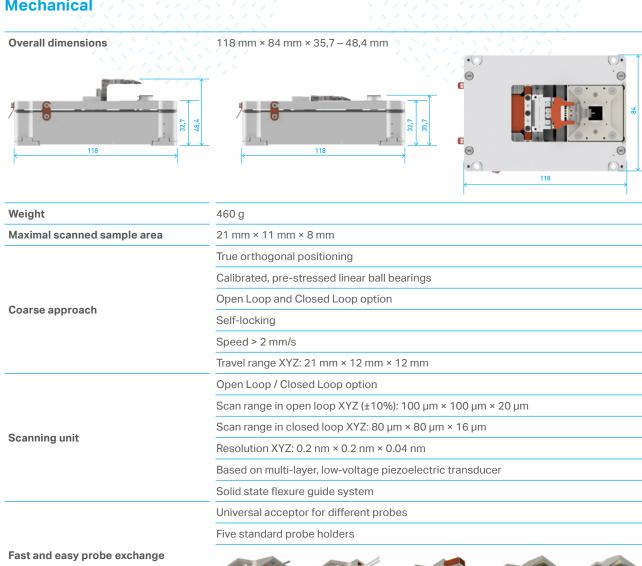


LiteScope™ Technical Specification

Environmental

Operating temperature	+10 °C to +35 °C	
Operating pressure	10 ⁻⁵ Pa to 10 ⁵ Pa	
Dry environment only		

Mechanical



Sample holder for standard SEM stubs (Ø12.7 mm with Ø3.2 mm and up to 6 mm long pin)

Two additional positions for SEM/FIB imaging/machining (not to be measured by AFM)

Operation and control system

Modes of operation	Topography and surface roughness, Energy dissipation (tapping mode), FMM (contact mode), F-z curves, nanoindentation, C-AFM, C-CPEM, KPFM, PFM, I-V spectroscopy, STM, MFM
Probes	Akiyama probe, Tuning-fork based probes, Piezoresistive probes, NenoProbes, etc.
Input channels could be used i	n feedback-loop
Probe signal output / monitor	
External probe excitation	
All necessary connections for	using external PLL
Ethernet connection to the cor	ntrol PC
110 VAC / 230 VAC operation,	200 W

Software

Web based user interface	
Easy for new users, flexible for	experts
User accounts	Every user has an account
	Accounts individually configurable – layout, parameters, complexity,
Remote access to the user dat	a, download of data from control PC to the local workstation
Remote experiment control via	eg. tablet, smartphone
Integrated data post-processir	ng, analysis, export, etc.

